In the Claims:

Please amend the claims as follows:

1-27. (Cancelled)

28. (Cancelled)

29. (Previously Presented) The process according to claim 55 in which a particle is placed in the focus or capture area to measure optically-induced forces, and the optically-induced forces are measured from the amplitude of the electrical field and the distance of the capture area from the focus when the particle moves from the focus to the capture area or vice versa.

30. (Previously Presented) The process according to claim 29 in which the optically-induced forces are repeatedly measured for all relevant directions in space corresponding to mutual alignment of said positions of said focus and said capture area.

31. (Previously Presented) The process according to claim 29 in which the optical cage is calibrated by determining a relationship between the light power to generate the optical cage and the forces induced on a particle in the optical cage.

32. (Previously Presented) The process according to claim 55 in which the distance between the focus and capture area is at least one-tenth of a particle diameter.

33. (Previously Presented) The process according to claim 55 in which the capture area is a capture point that is in a beam field of the optical cage so that the at least one particle moves back and forth between the capture point and focus when the amplitude of one of the electrode signals and light power is varied, and an associated value of the amplitude is used to measure the optically-induced forces.

34. (Previously Presented) The process according to claim 55 in which numerous particles are sequentially injected with said optical cage into said capture area, wherein said particles are

positioned in predetermined positions within the capture area relative to other particles in the capture area.

35. (Previously Presented) The process according to claim 55 in which the light beam of the optical cage is adjusted and one of a capture quality and symmetry of the optical cage are measured.

36. (Previously Presented) The process according to claim 55 in which passive electric properties of said at least one particle are characterized based on the measured optically-induced forces.

37. (Cancelled)

38. (Previously Presented) The process according to claim 55 in which an electrode of the microelectrode arrangement is alternatively supplied with at least one of signals phase-shifted 180° and rotation-generating signals with a predetermined phase division.

39. The process according to claim 55 in which at least one field barrier is formed between said capture point and said optical cage.

40. (Previously Presented) The process according to claim 55 in which a particle movement is detected by one of optical and electrical detection.

41. (Previously Presented) The process according to claim 55 in which the particles are synthetic or natural particles with a size less than 200 μm.

42. (Previously Presented) The process according to claim 55 in which the particles are biological cells or their components.

43. (Previously Presented) The process according to claim 55 in which the movement of the particle between the capture area and the focus is used to adjust the optical cage.

44. (Cancelled)

45. (Cancelled)

46. (Cancelled)

47. (Cancelled)

48. (Cancelled)

49. (Cancelled)

50. (Cancelled)

51 (Cancelled)

52. (Cancelled)

53. (Previously Presented) Calibrating a laser tweezer by exerting optically-induced forces on at least one particle and measuring said forces with a procedure according to claim 55.

54. (Cancelled)

55. (Previously Presented) A procedure to exert or measure optically-induced forces which are capable of moving at least one particle or holding at least one particle in a focus of an optical cage formed with a light beam, comprising:

a) positioning the focus in a microelectrode arrangement in which an electrical field is formed that has a field gradient which forms a three-dimensional electrical capture area, said electrical capture area representing an electrical field cage with a capture point at a minimum electrical field level of the capture area, wherein the focus is positioned at a distance from the capture point

b) positioning said at least one particle at one of the focus and the capture point,

c) varying at least one parameter selected from an amplitude of said electrical field, a light power of said light beam and the distance of the capture point from the focus until the particle moves between the focus and the capture area, and

d) exerting said optically-induced forces, wherein said at least one particle is at least temporarily moved between the focus and the capture area, or measuring said optically-induced forces, wherein said at least one parameter varied in step c) is detected when said at least one particle moves between the focus and the capture point.

56. (Cancelled)